



FROM POWER PACKAGES TO 3D INTEGRATION : THE THERMAL CHALLENGE

Journée Thématique :

**Caractérisations Thermo-physiques et
applications micro-électroniques**

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Innovation Drivers and Consequences



+Functionality: camera, radio, TV, GPS, games, internet. ==> *integration*

+Mobility: reduced form factor, weight... ==> *miniaturization*

+Performance: pixels, speed, reliability, less energy greedy.. ==> *techno. breakthroughs*

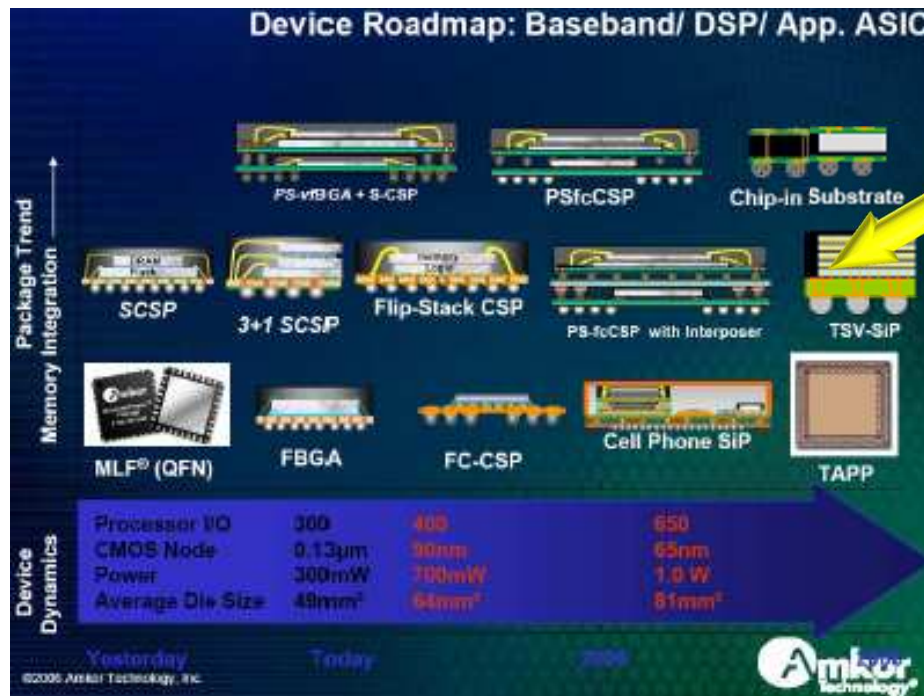
-Price: more for less ==> *cost reduction*

Weight 3X less
Volume 5X less

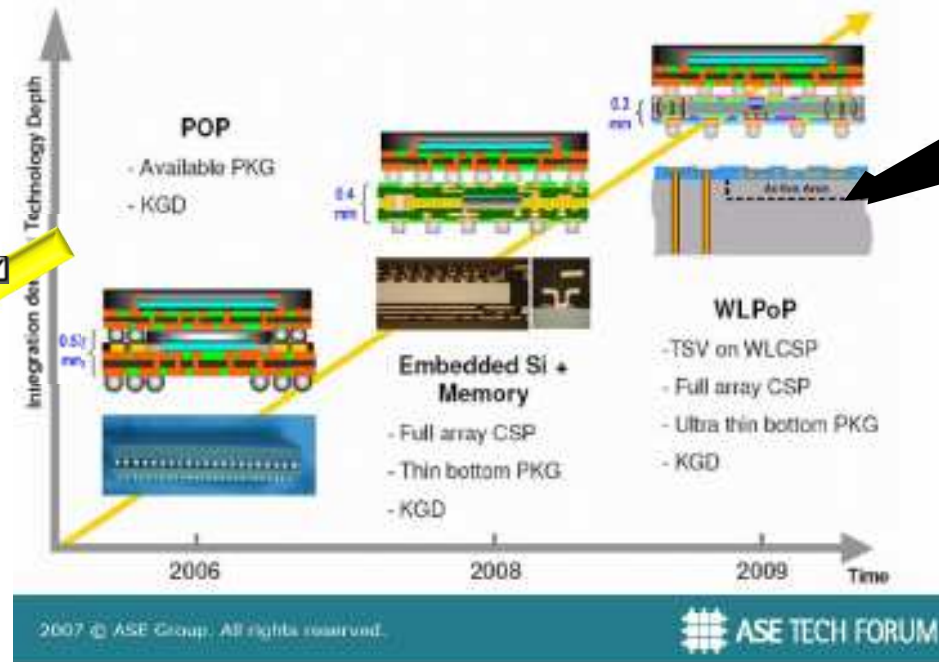
3D PACKAGING ROADMAPS



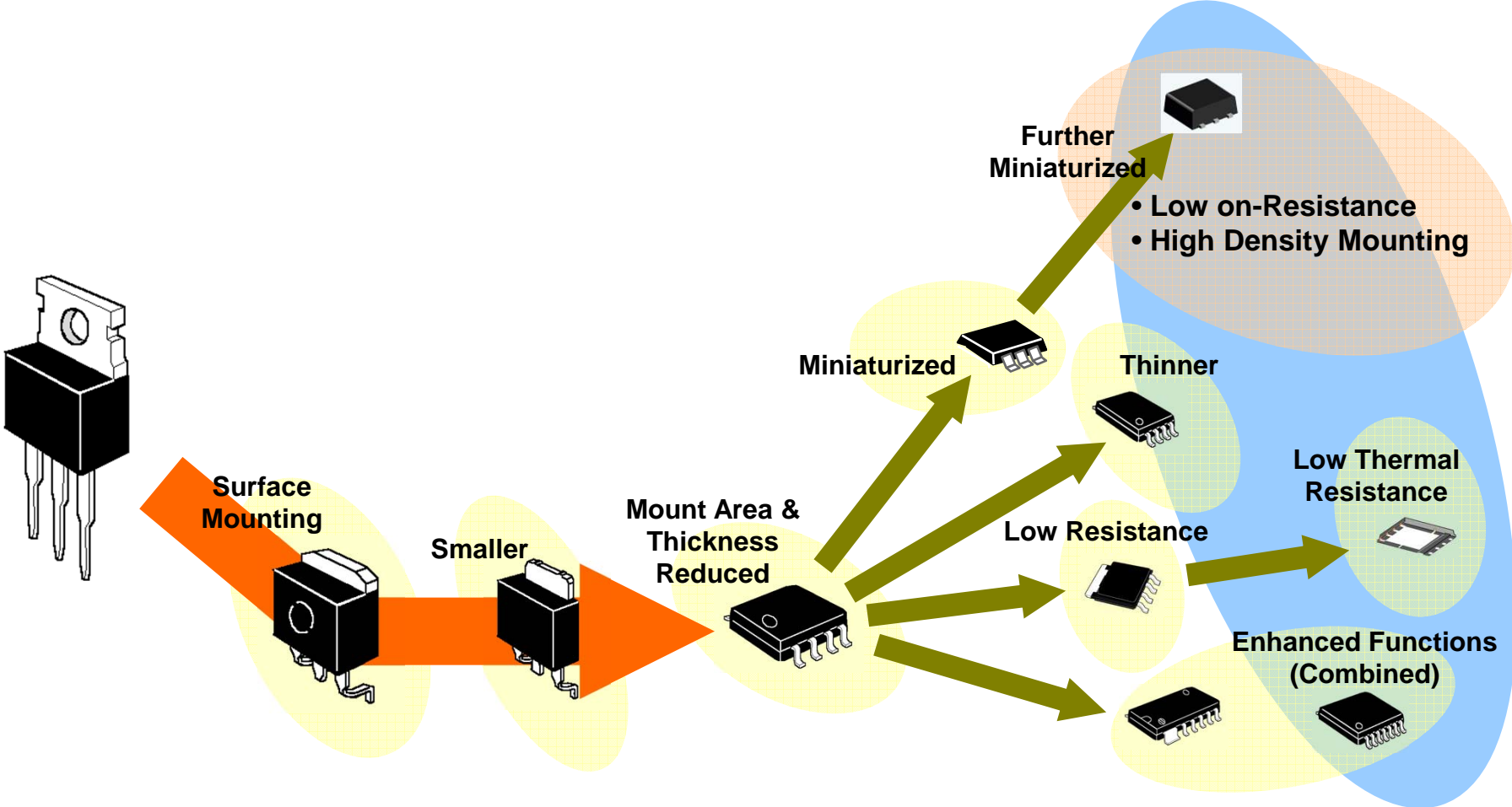
AMKOR



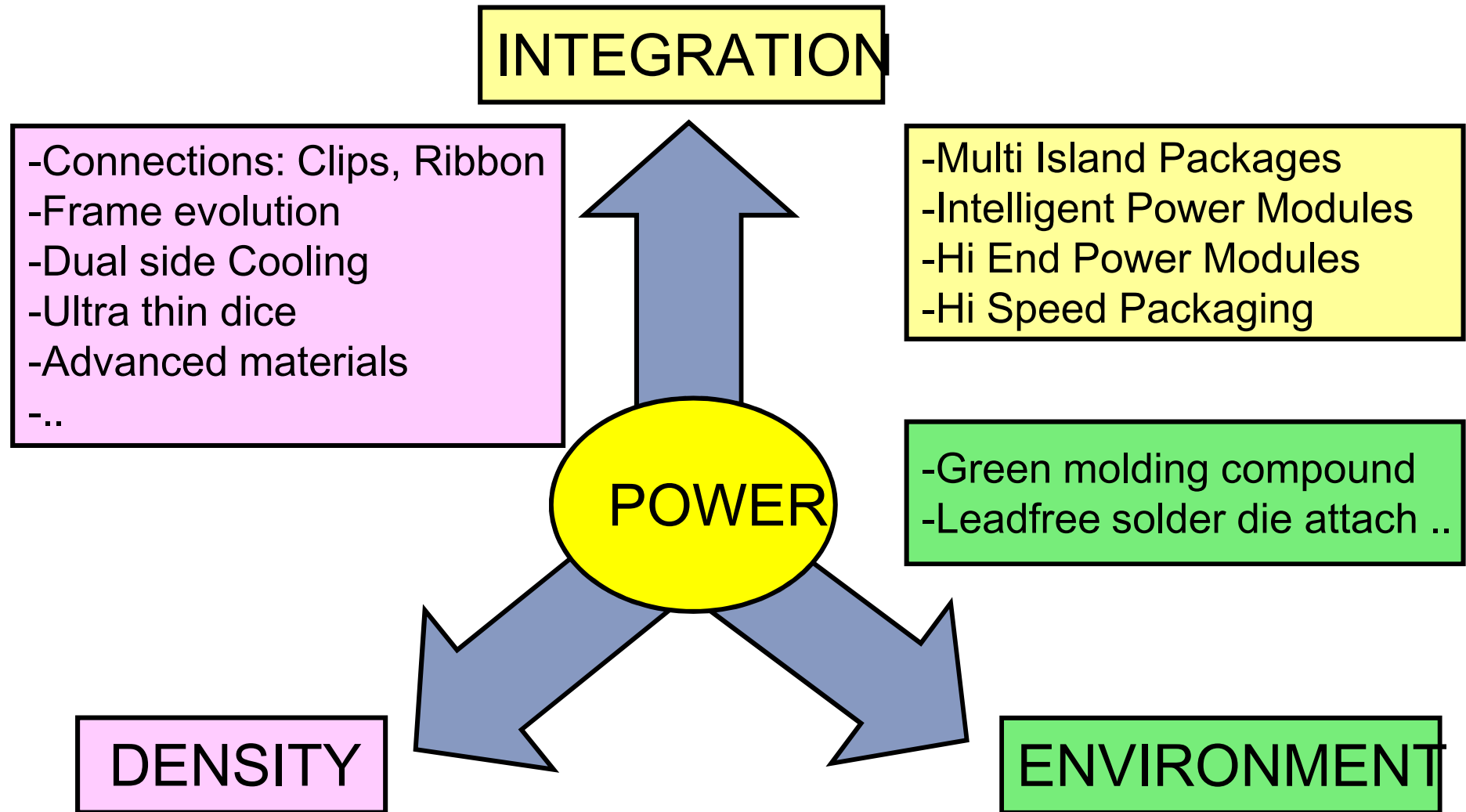
ASE



POWER PACKAGING CHANGES



KEY AXES OF POWER PACKAGING DEVELOPMENT

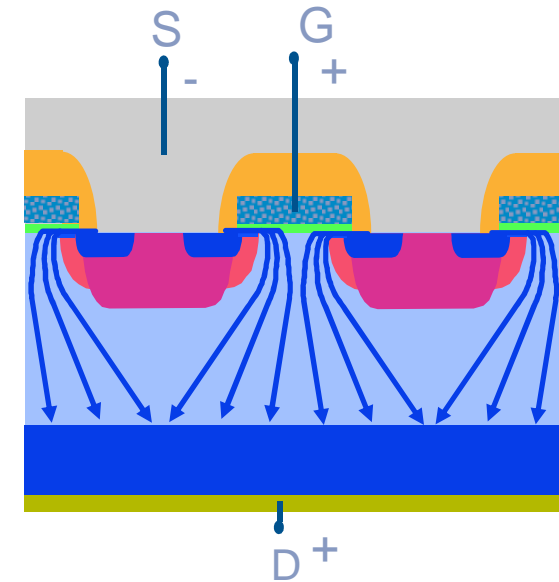


HEAT EFFECT : THE CHALLENGE!



- Electric Power $\rightarrow P_e = R_{on} * I^2$
- Dissipated Power $\rightarrow P_d = (T_j - T_c) / R_{thj}$

$P_d = P_e \rightarrow$ Minimum R_{on} , Minimum R_{th}



PMOS example

Key Factors for Power Packaging Efficiency

- ▣ Interconnections
- ▣ Die Attach
- ▣ Materials

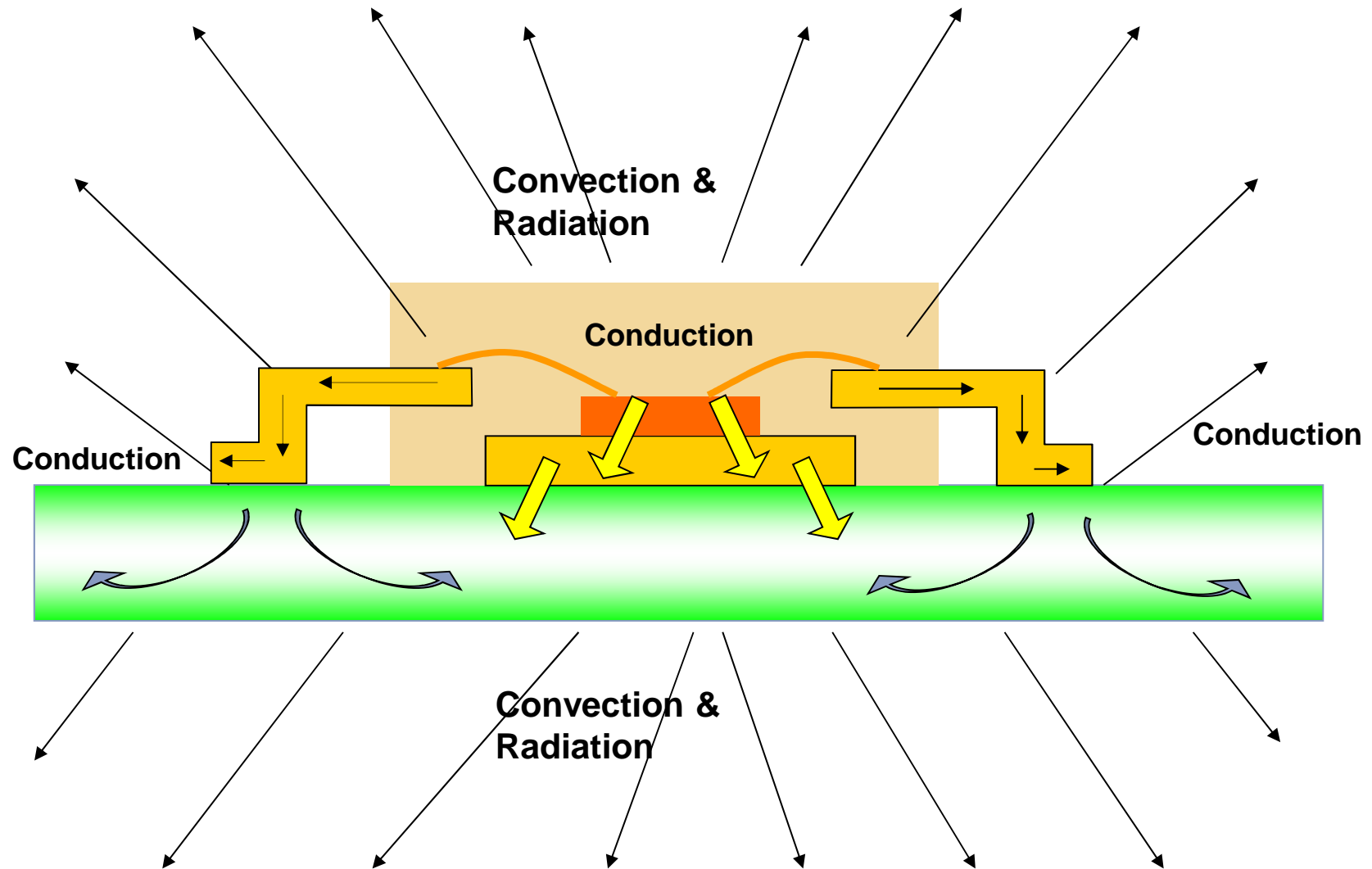
➤ NATURAL WAYS

- **Conduction** : heat transfer mechanism due to thermal excitation at molecular level, by direct contact. No motion of material is associated to this mechanism
- **Radiation** : transport of electromagnetic energy
- **Natural convection** : transfer of heat associated with the movement of material in a fluid (liquid or gas).

➤ FORCED WAYS

- **Forced convection**
- **Components able to absorb heat with power (Pelletier effect, refrigerating machines)**
- **Use of some materials 's latent heat of phase change (caloducs, thermo-siphons, fluids evaporation, etc...)**

HEAT DISSIPATION MODES



MATERIALS THERMAL CONDUCTIVITY



➤ **Silicium** $\frac{1}{\sigma} = 3.14 * 10^{-3} * T^{-0.219}$ ie 140W/mK@25°C, 113W/mK@100°C & 88W/mK@150°C

➤ **Glass** = 1.2 W/m.k

➤ **Sapphire** = 42 W/m.k

➤ **Copper** = 260 to 400 W/m.K

➤ Alloy 194 = 260

➤ KFC, FPG = 360

➤ Cub2 = 370

➤ Cua1= 390

➤ Alloy42 (FeNi) = 40

➤ **D/A materials**

➤ PbSnAg = 30 to 45

PbSn5Ag1.5 = 42, PbSn5Ag2.5=44, SnPb37=70

➤ Silver glue = 2 to 6

➤ **Resins**

➤ Standard EMC (fused silica) = 1

➤ Conductive EMC (crystallized silica) = 2.5

➤ **Ceramics**

➤ Al₂O₃ = 20 to 25

➤ AlN = 170-180

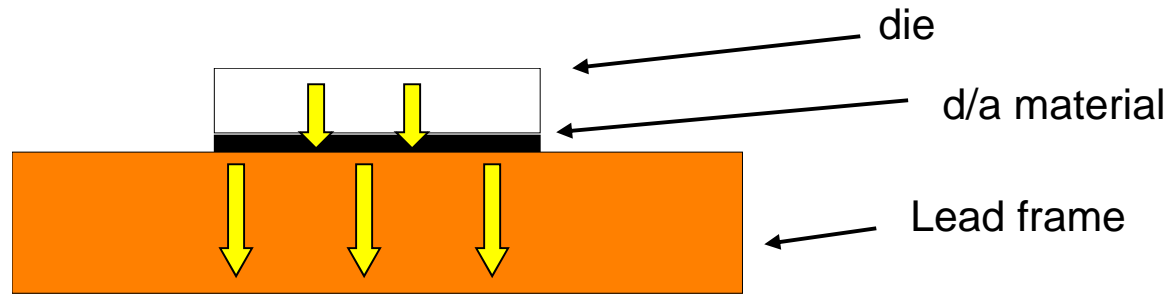
➤ **Wires**

➤ Al = 200

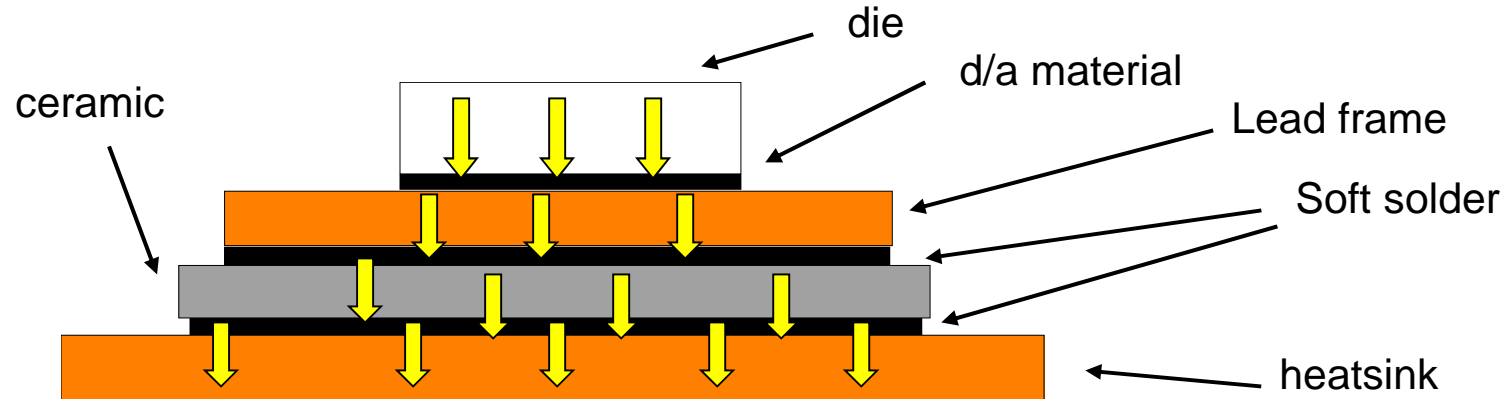
MULTIPLE INTERFACES EFFECT ON Rth



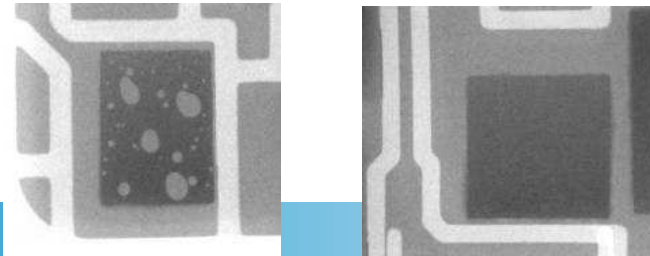
NON INSULATED PACKAGES (TO220, TO247, DPAK,...)



CERAMIC INSULATED PACKAGES (TO220I, TOP3, RD91,...)



SOLDER JOIN QUALITY



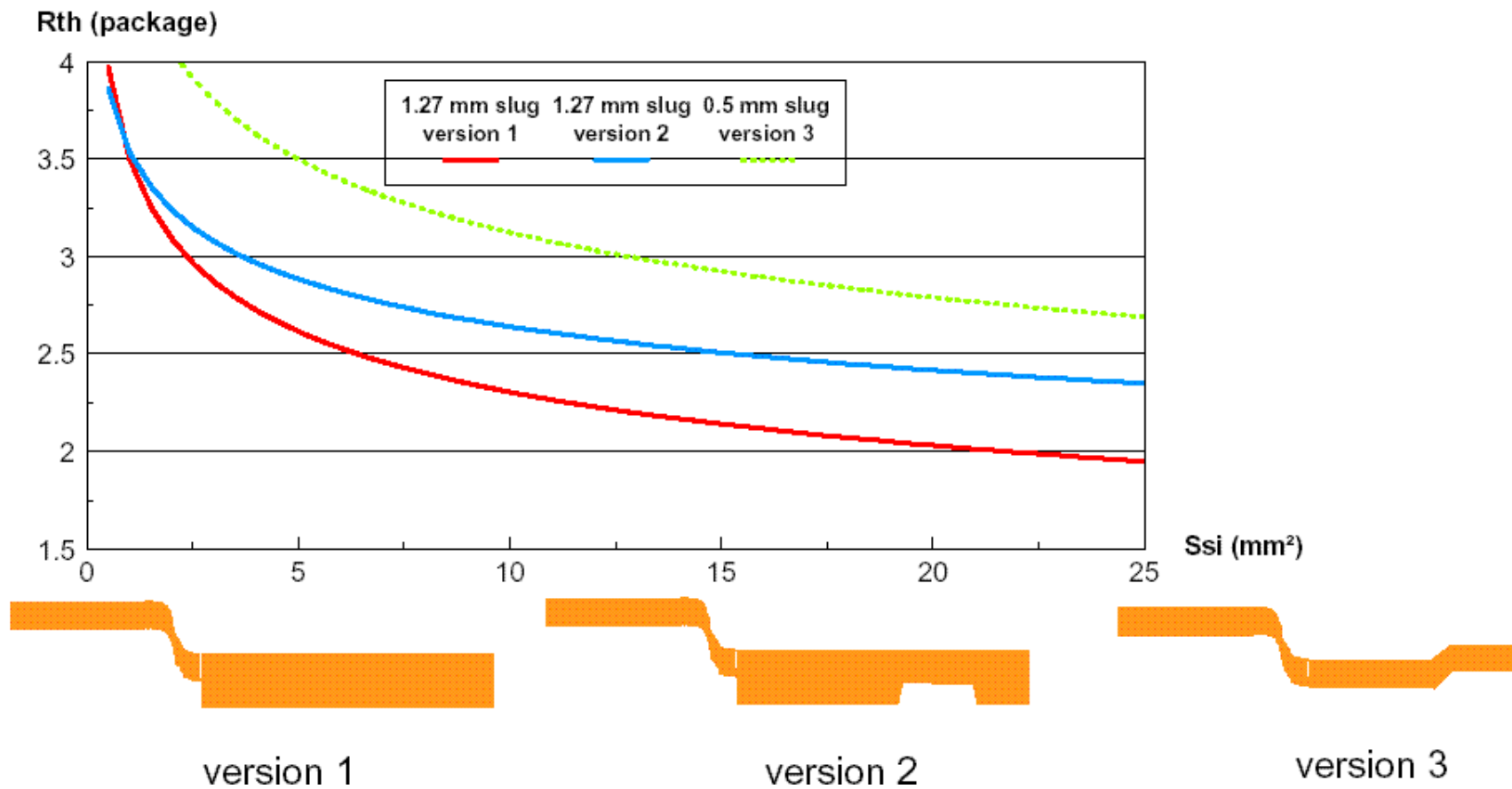
DIE THICKNESS REDUCTION



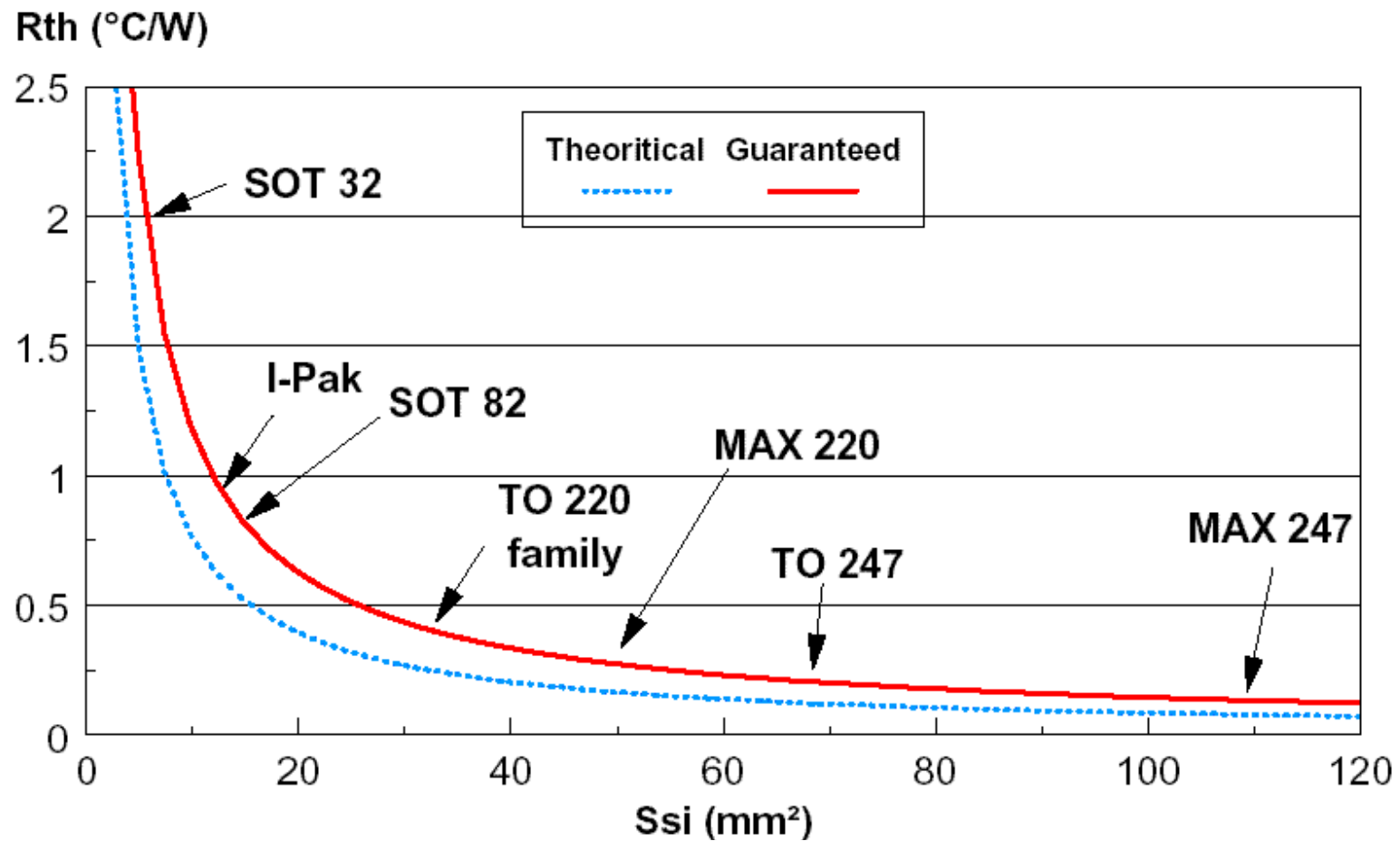
- To improve the thermal performance of our devices by reducing the silicon thickness
- Special F/E-B/E manufacturing process to solve the warpage and the handling problem that occurs when we reduce the wafer thickness down to 100 μ m or below



COPPER LEAD-FRAME DESIGN EFFECT ON Rth



PACKAGE SIZE EFFECT ON Rth



with die thickness of 300 μ m, periphery of 200 μ m & σ (Si) of 110 W/mK

EXTERNAL HEATSINK INFLUENCE



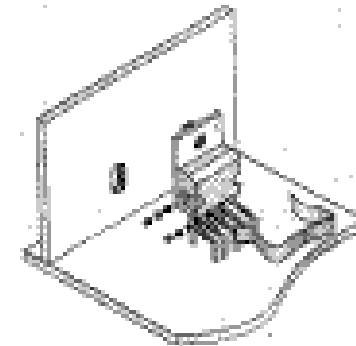
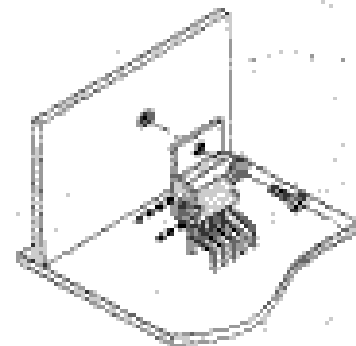
❑ Non insulated Insertion packages (TO220, TO247,...)

- ❑ Inserted in through hole technology boards
- ❑ Secured to external heatsink using screws or clip (cheaper)

❑ Insulated insertion packages (ISOWATT220, ISO218, ..)

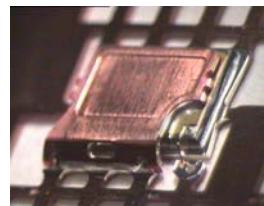
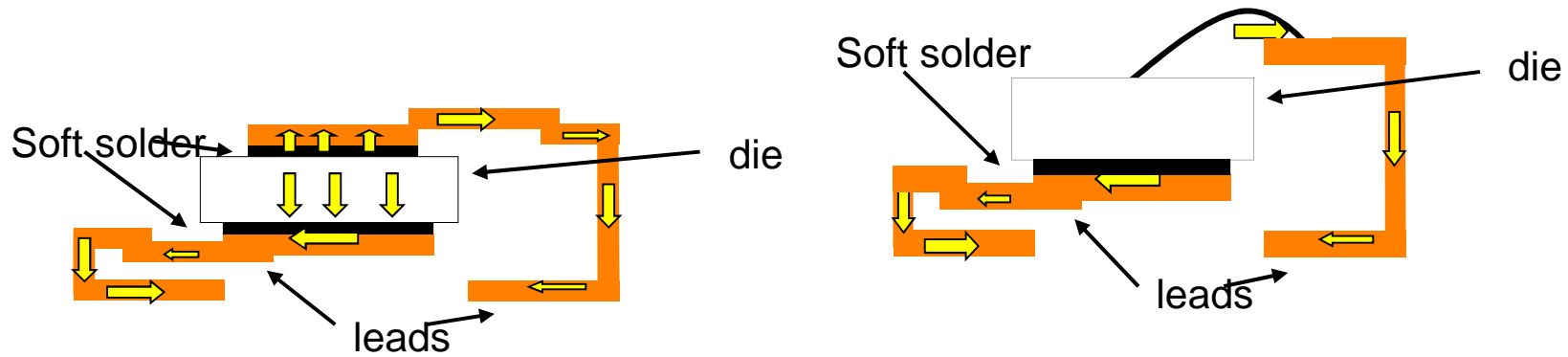
- ❑ When insulation is mandatory, thin sheet of mica or adhesive mylar can be placed between slug and heatsink

Problem : thermal performance inconsistent (variations in thickness, position and adhesion of the insulating sheet)

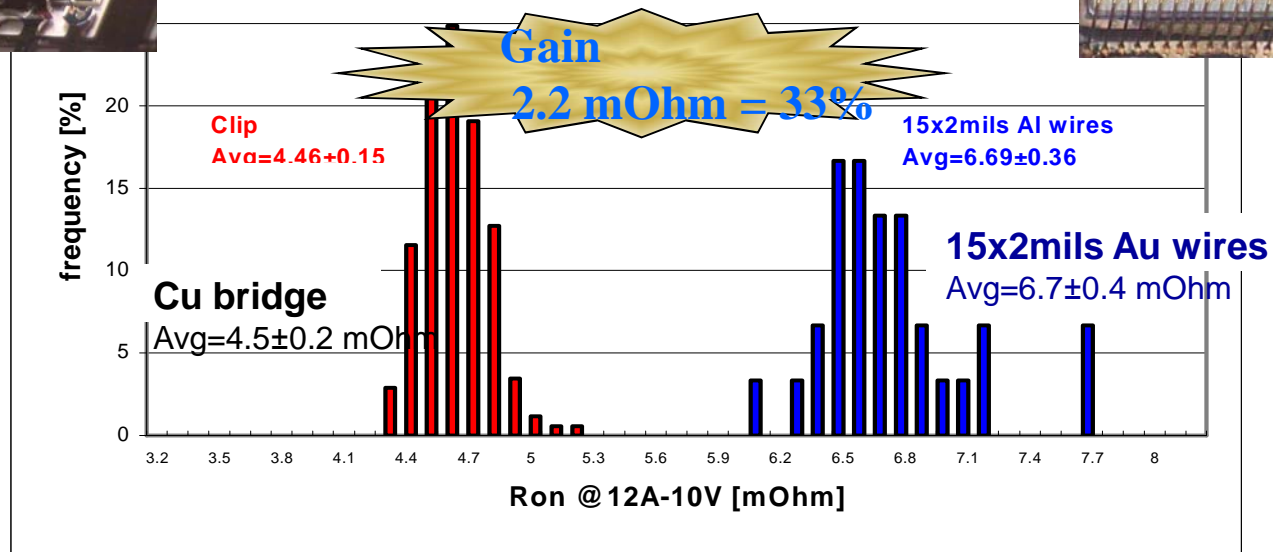
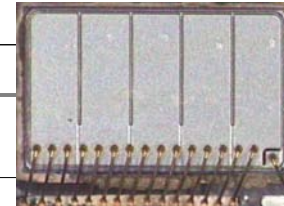


PACKAGE	ISOLATION	Rthj-c °C/W
TO-220	none	1.3
TO-220	100mm mica	3.3
TO-220	mylar	4.4
ISOWATT220	none	3.0
ISOWATT221	none	3.8
ISOWATT218	none	2.1

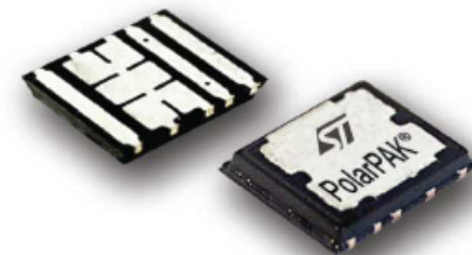
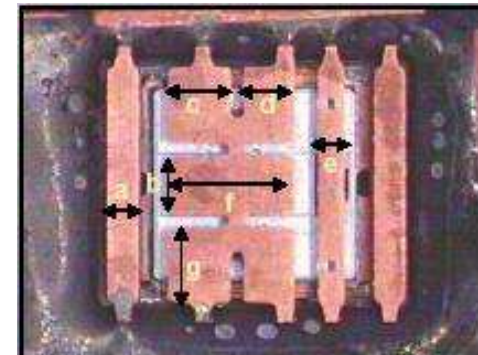
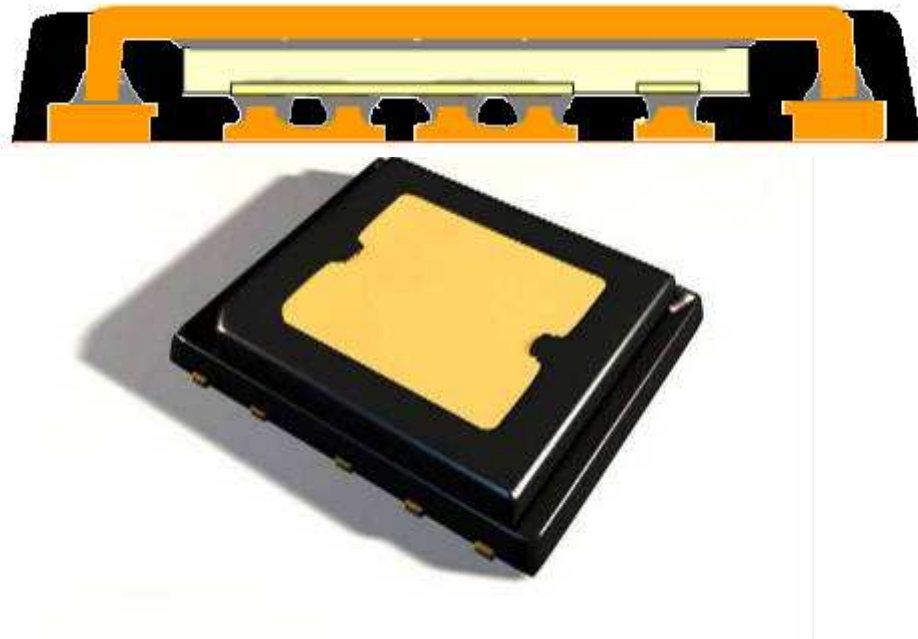
DIE TOP INTERCONNECTION EFFECT ON Rth



SO8

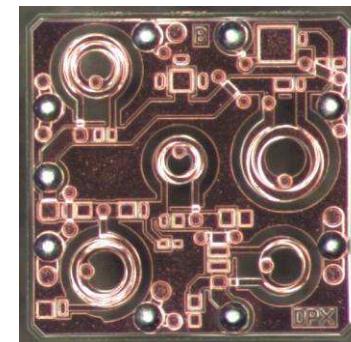
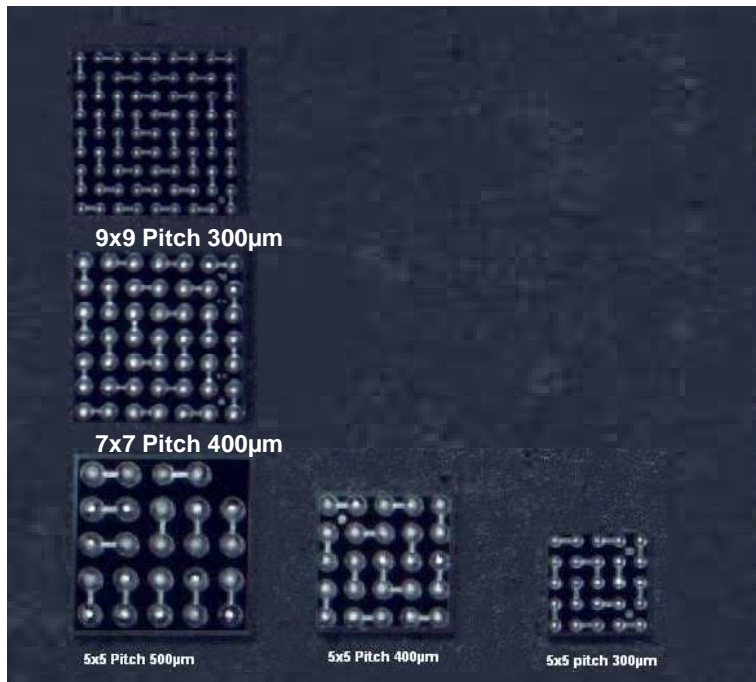
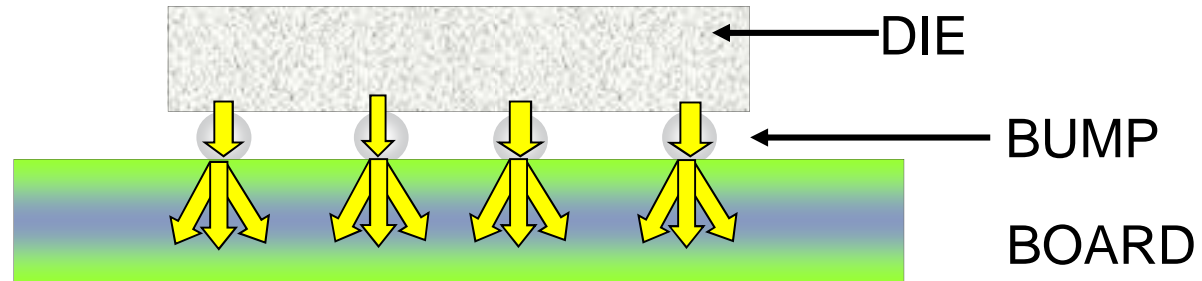


DUAL SIDE COOLING

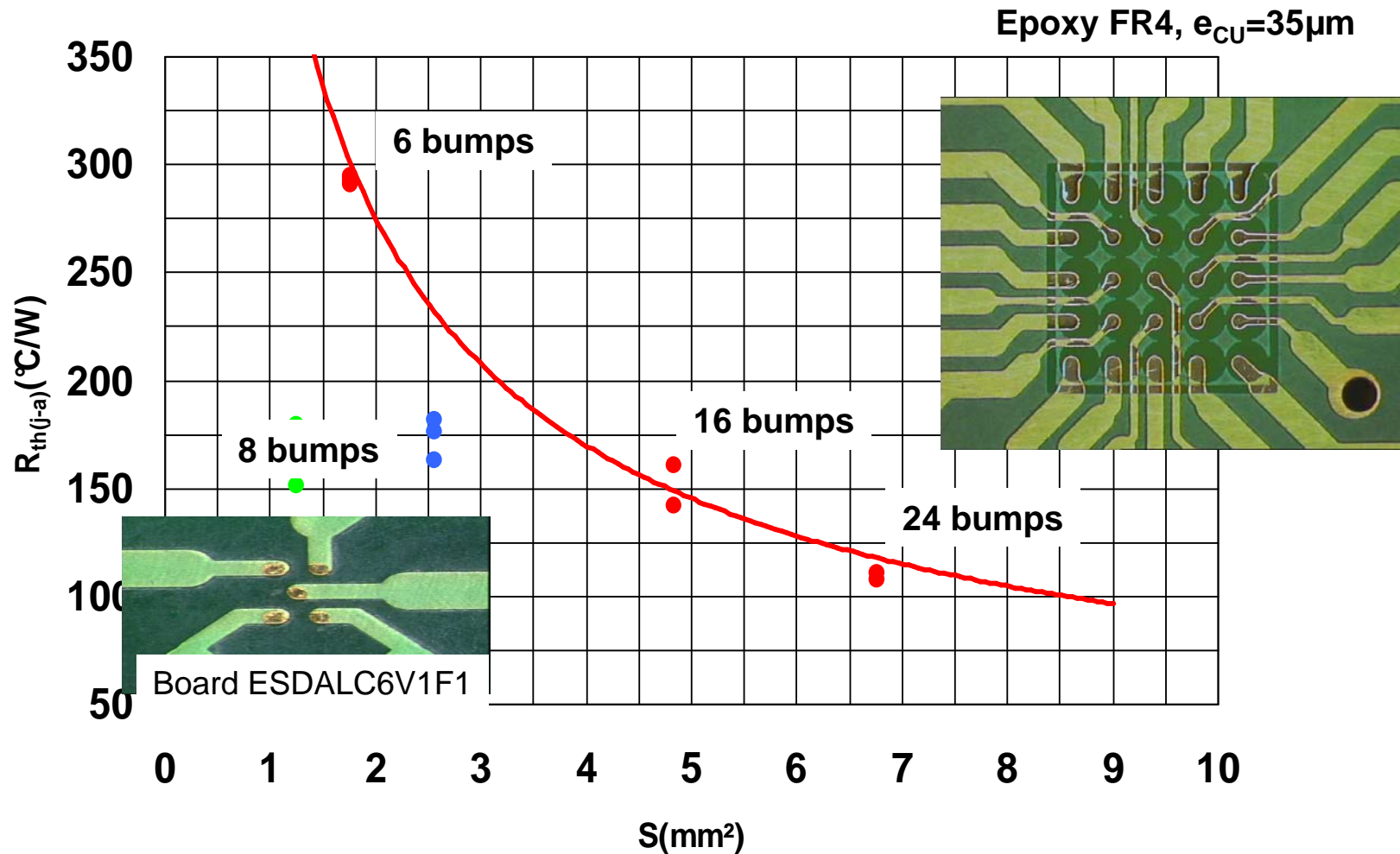


Rth improvement: Dissipation by Top

WAFER LEVEL SIMILARITIES



DIE SIZE / IO NUMBER EFFECT ON Rth



Thermal resistance junction to ambient versus die surface (typical values)

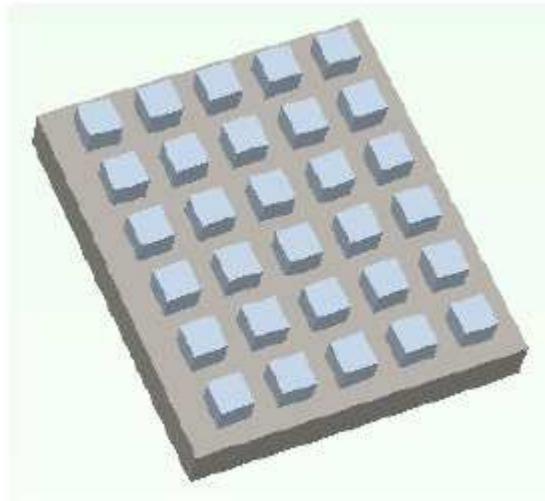
PRINTED WIRING BOARD EFFECT ON Rth



	D-Pak Rth (j-a)	D ² -Pak Rth (j-a)
On infinite heatsink	2.5 °C/W	1 °C/W
FR4	65 °C/W	50 °C/W
FR4 with 10 cm ² on board heatspreader	40 °C/W	35 °C/W
FR4 with copper filled holes on heatsink	13.5 °C/W	12 °C/W
IMS floating in air	9.5 °C/W	8 °C/W
IMS with external heatsink	4.5 °C/W	3 °C/W

assuming a heatsink of 2 °C/W

CASE STUDY : DESIGN PARAMETERS EFFECT ON Rth

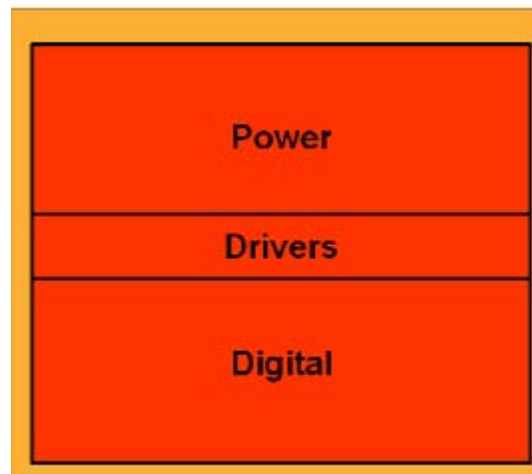


Package bottom view

WCSP 3.1x2.7x0.65 mm

30 balls / Lead free
 (5x6 matrix)
 0.3 mm diameter
 0.5 mm pitch

die size = 3.102 x 2.738 mm
 die thickness = 400 μ m



Source	Area (mm ²)	Power (mW)
Power	2.85	760
Drivers	1.02	665
Digital	3.09	165

Total Area = 6.97 mm²

Total Power = 1.59 W

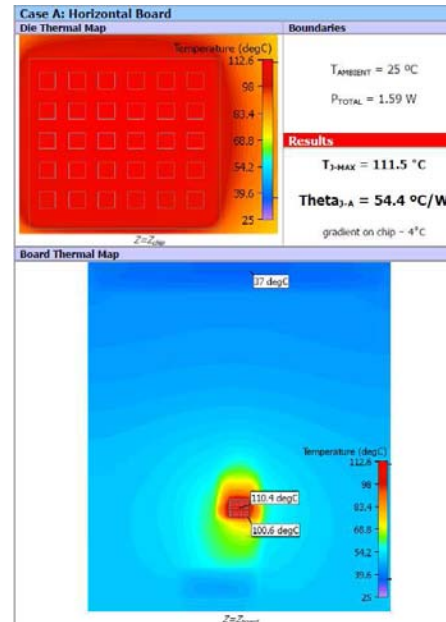
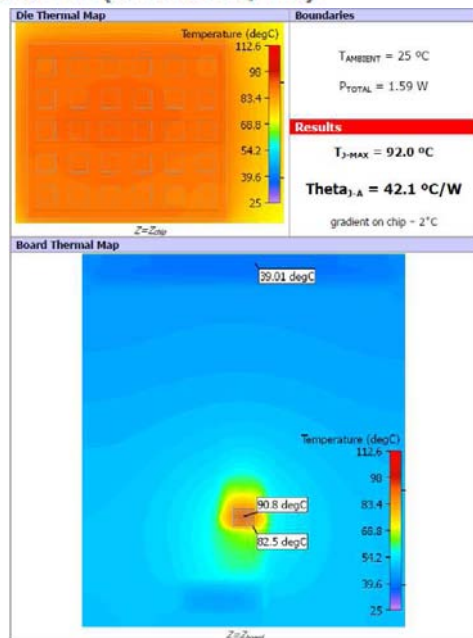
THE CONDUCTION EFFECT IS KEY



Steady State Conditions

Different cases have been evaluated:

- **CASE A:** Horizontal board
- **CASE B:** Vertical board
- **CASE C:** Bar instead of balls
- **CASE D:** Die thickness 200 μm instead 400 μm
- **CASE E:** Layer thickness 2 oz. instead 1 oz.
- **CASE F:** Underfill ($k = 0.4 \text{ W/mK}$)



Case	Difference to Case A
Case A (Horizontal Board)	---
Case B (Vertical Board)	-2.9 %
Case C (Bar)	+0.5 %
Case D (Die Tck 200 μm)	+1.3 %
Case E (Layer Tck 2 oz.)	-22.5 %
Case F (Underfill)	-0.4 %

- ❑ Electro migration

- ❑ Black's law

$$TTF = A \cdot J^{-N} \cdot \exp\left(\frac{E_a}{k \cdot T}\right)$$

- ❑ Key factors :

- ❑ Current Density J

- ❑ Temperature T

- ❑ Main failure mode :

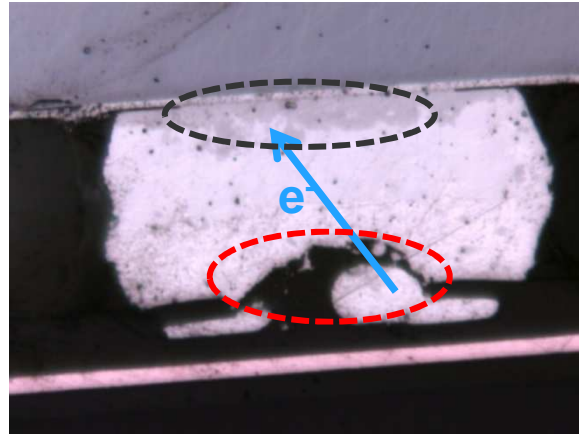
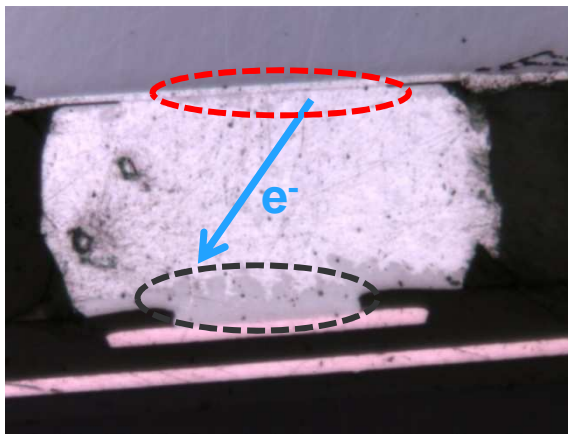
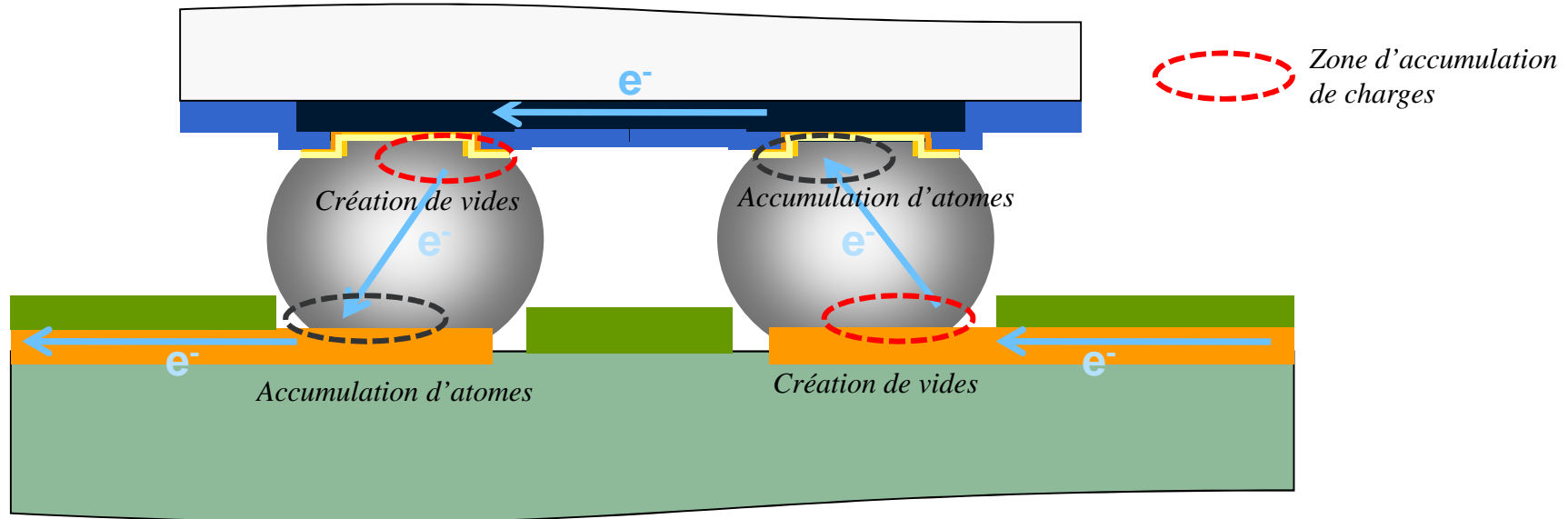
- ❑ Current crowding in some particular location heats the structure.

- ❑ Voids are created, increasing the current density and the heating of the structure

- ❑ Thermo migration

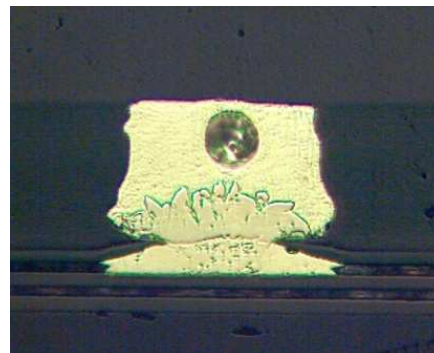
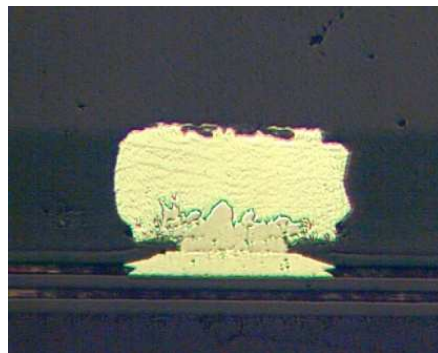
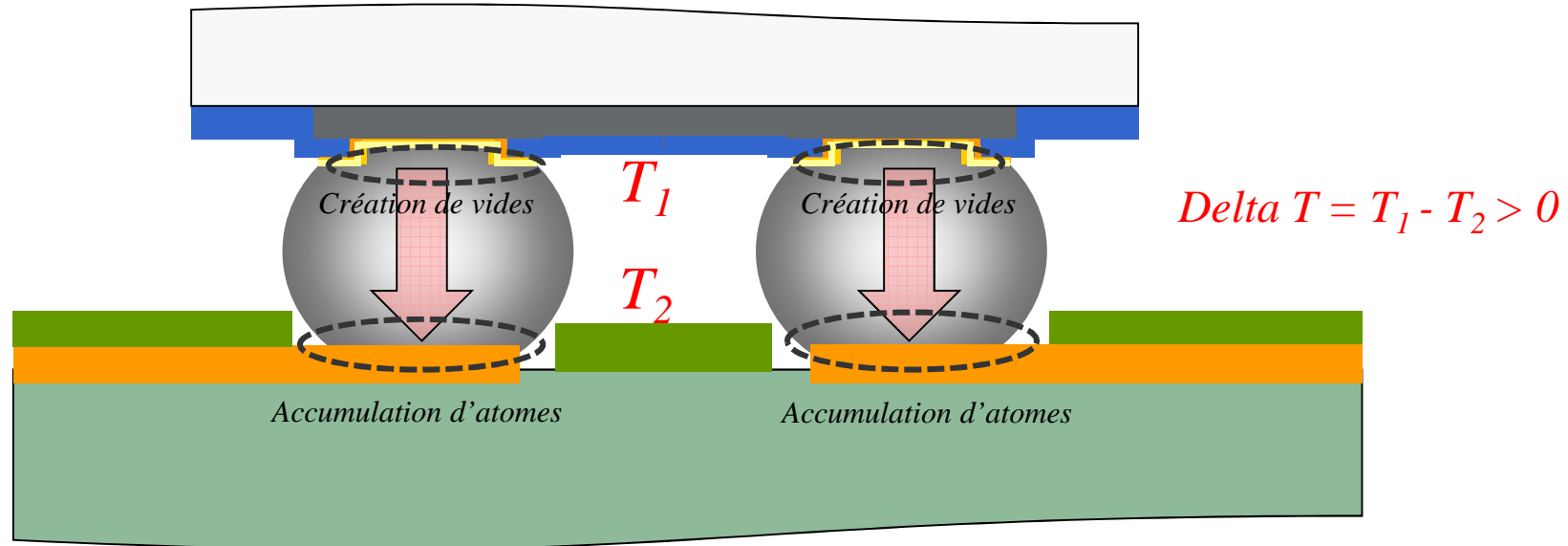
- ❑ The component ambient operating temperature can drastically influence the aging speed. Especially a temperature gradient between the component and the board (from 0.15°C/μm) can damage the bump

ELECTROMIGRATION EFFECT



*Courant électrique = 400mA
T ambiante = 125 °C
Microsection @ 320 hours
Bossage en SnAg4Cu0.5*

THERMOMIGRATION EFFECT



Pas de Courant électrique
Delta T = 0.2 °C/μm
Microsection @ 60 hours
Bossage en SnAg4Cu0.5

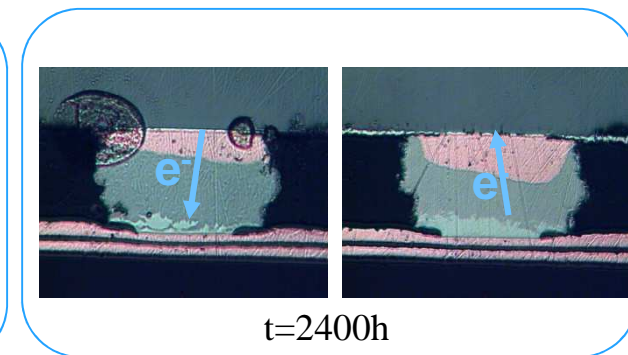
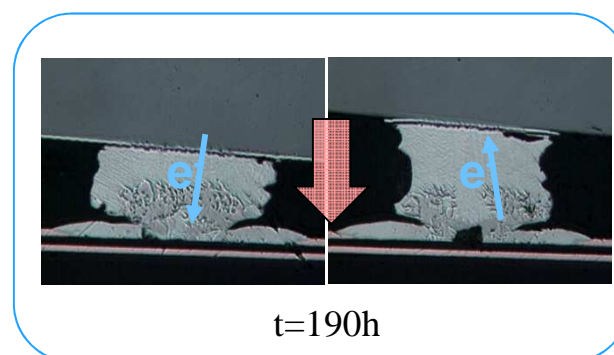
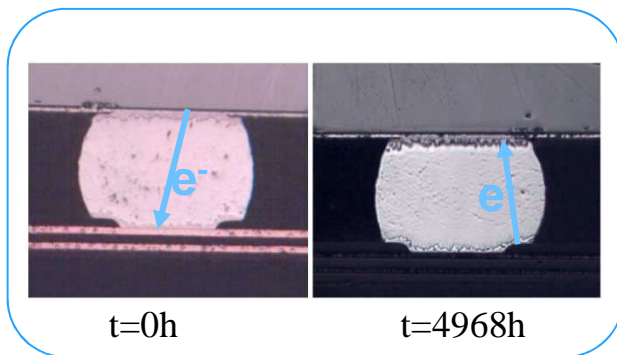
COMPONENT DESIGN EFFECT



Daisy Chain Component
 ⇒ No Heating
 ⇒ Solder Bump

Active Component
 ⇒ Heating
 ⇒ Solder Bump

Active Component
 ⇒ Heating
 ⇒ Copper Pillar Bump
 (Low Bump Rth)



Scenario 1

$T_a = 25\text{ }^\circ\text{C}$
 $T_j = 30\text{ }^\circ\text{C}$
 $I = 240\text{mA}$
 $J = 0.12\text{mA}/\mu\text{m}^2$
 $\text{Grad } T = 0.001\text{ }^\circ\text{C}/\mu\text{m}$

No Defect@ 4968h

Scenario 2

$T_a = 25\text{ }^\circ\text{C}$
 $T_j = 156\text{ }^\circ\text{C}$
 $I = 240\text{mA}$
 $J = 0.12\text{mA}/\mu\text{m}^2$
 $\text{Grad } T = 0.295\text{ }^\circ\text{C}/\mu\text{m}$

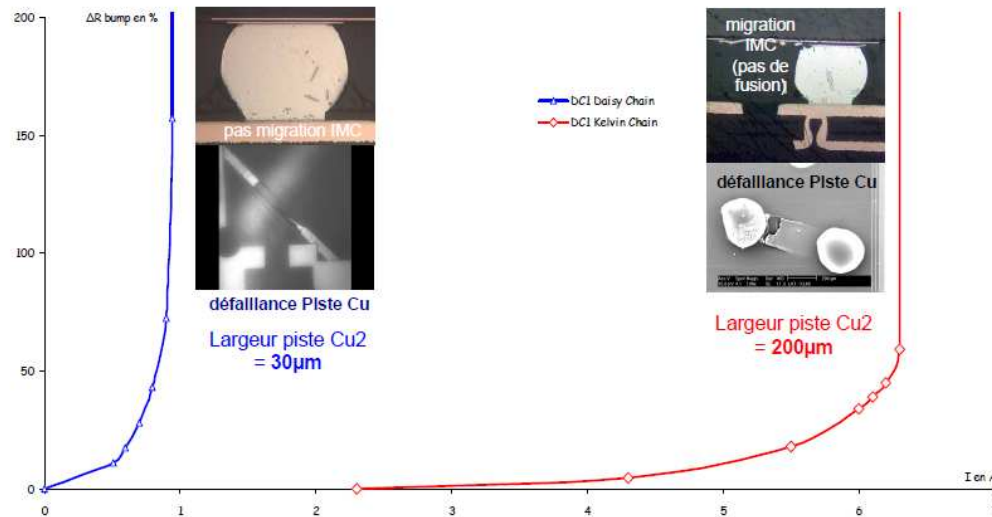
1st Defect @ 180h
 $\text{TTF}_{63.2\%} = 245\text{h}$

Scenario 3

$T_a = 25\text{ }^\circ\text{C}$
 $T_j = 164\text{ }^\circ\text{C}$
 $I = 240\text{mA}$
 $J = 0.12\text{mA}/\mu\text{m}^2$
 $\text{Grad } T = 0.114\text{ }^\circ\text{C}/\mu\text{m}$

No Defect@ 2400h

- From 1 Amp to >6 Amps for the same bump => pad & trace influence

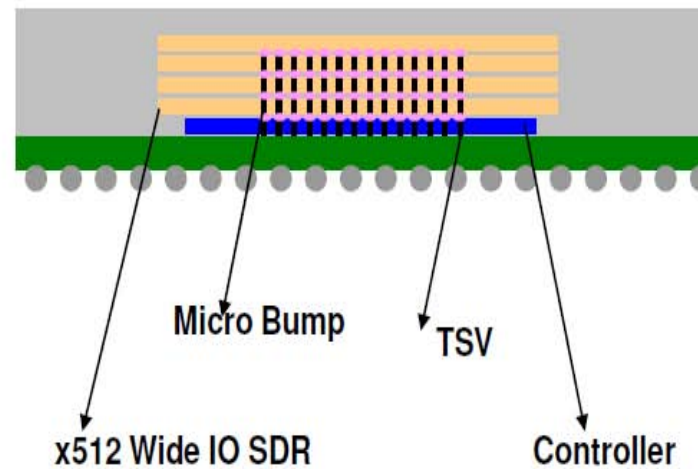
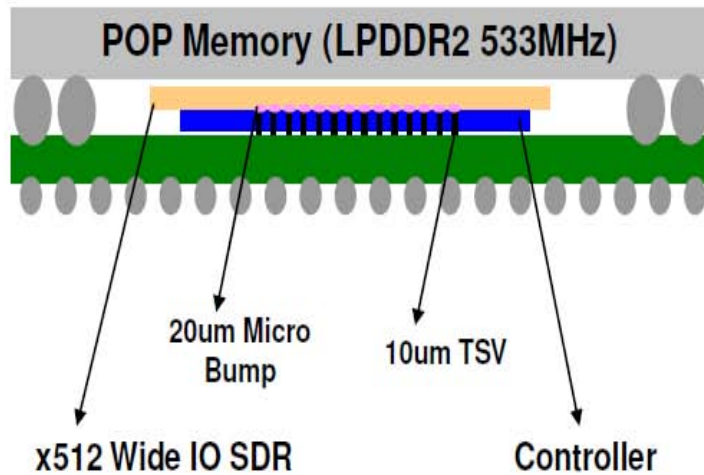
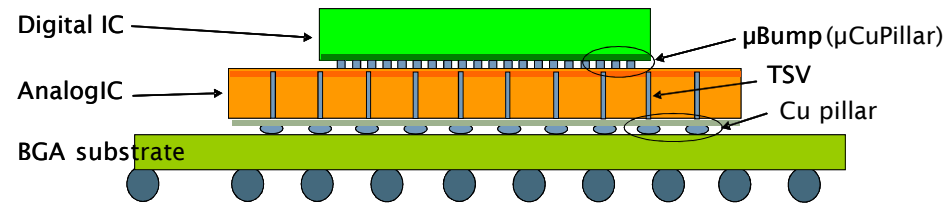
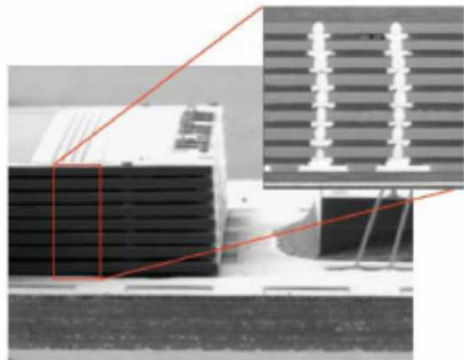


Resulting from the Joule effect, either the bump or the component structure can be heated and in certain the extend fuse.

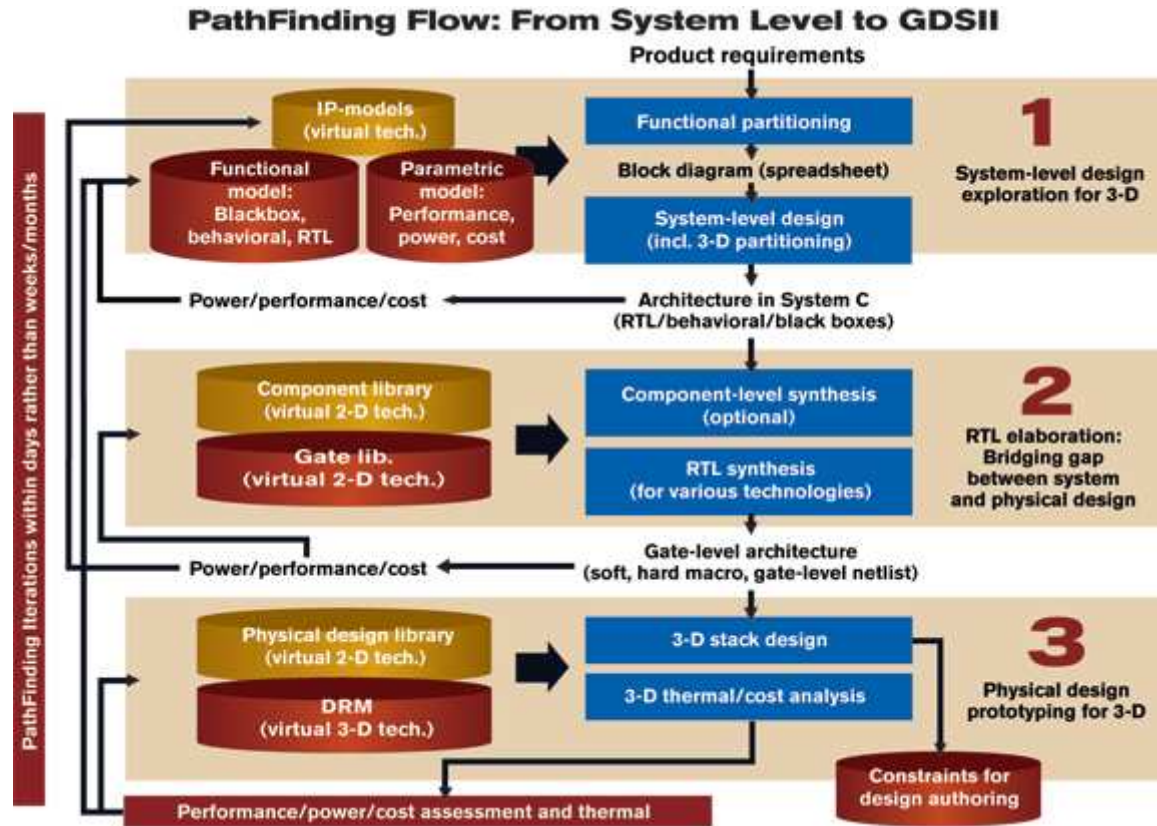
Key parameters are :

- The bump material
- The bump size
- The component and PWB design (Line width, Line thickness, Thermal vias,...)
- The component and the PWB materials (Glass, Silicon, ...)

3D COMPONENT = 3X COMPLEXITY



3D DESIGN CHALLENGES: THINK GLOBAL



Main shift in Design paradigm:
3D means to think B-E and F-E at the same time



THANK YOU!